



Docket No.: 1514.1032

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
EXPEDITED PROCEDURE PURSUANT
TO 37 CFR §1.116 REQUESTED
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In re the Application of:

Ji Yong PARK et al.

Serial No. 10/690,507

Group Art Unit: 1722

Confirmation No. 6043

Filed: October 23, 2003

Examiner: Song, Matthew J.

For: **METHOD FOR MANUFACTURING POLYCRYSTALLINE SILICON THIN FILM AND
THIN FILM TRANSISTOR FABRICATED USING POLYCRYSTALLINE SILICON THIN
FILM MANUFACTURED BY THE MANUFACTURING METHOD**

AMENDMENT AFTER FINAL

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

February 28, 2007

Sir:

This is in response to the Office Action mailed November 1, 2006, and having a period for response set to expire on February 1, 2007.

The following amendments and remarks are respectfully submitted. Reconsideration of the claims is respectfully requested.

03/01/2007 JADD01 00000052 10690507
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